

Milan Tichy

List of Publications by Year in descending order

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2,585
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172457

29
h-index

243625

44
g-index

151
all docs

151
docs citations

151
times ranked

1647
citing authors

#	ARTICLE	IF	CITATIONS
1	Ion temperature measurements in the tokamak scrape-off layer with high temporal resolution. Nuclear Fusion, 2021, 61, 036023.	3.5	5
2	Magnesium-silver cathodes for efficient charge injection into Organic Light Emitting Diodes deposited by LTVA method. Journal of Alloys and Compounds, 2021, 869, 159364.	5.5	8
3	Plasma Diagnostics in Reactive High-Power Impulse Magnetron Sputtering System Working in Ar + H ₂ S Gas Mixture. Coatings, 2020, 10, 246.	2.6	2
4	Thermionic Vacuum Arc – A Versatile Technology for Thin Film Deposition and Its Applications. Coatings, 2020, 10, 211.	2.6	28
5	Iron Oxide and Iron Sulfide Films Prepared for Dye-Sensitized Solar Cells. Materials, 2020, 13, 1797.	2.9	12
6	Ablation of single-crystalline cesium iodide by extreme ultraviolet capillary-discharge laser. Nukleonika, 2020, 65, 205-210.	0.8	0
7	In-situ impedance spectroscopy of a plasma-semiconductor thin film system during reactive sputter deposition. Journal of Applied Physics, 2019, 126, 023301.	2.5	3
8	Plasma diagnostics and characterization of the Mg and Mg-Zn thin films deposited by thermionic vacuum arc (TVA) method. Vacuum, 2019, 167, 129-135.	3.5	6
9	Registration of a laser beam scattered from an aerosol located in the probe beam aperture. AIP Conference Proceedings, 2019, , .	0.4	0
10	Particularities of Cu and Zn nanoparticles formation in a magnetic field. , 2019, , .		2
11	Floating harmonic probe for diagnostic of pulsed discharges. Surface and Coatings Technology, 2019, 357, 879-885.	4.8	3
12	Floating harmonic probe measurements in the low-temperature plasma jet deposition system. Journal Physics D: Applied Physics, 2018, 51, 025205.	2.8	6
13	Electron energy distribution function in a low-power Hall thruster discharge and near-field plume. Physics of Plasmas, 2018, 25, .	1.9	8
14	Monitoring of conditions inside gas aggregation cluster source during production of Ti/TiO ₂ nanoparticles. Plasma Sources Science and Technology, 2017, 26, 105003.	3.1	15
15	Heterogeneous Arc Discharge Plasma in a Magnetic Field. Russian Physics Journal, 2017, 60, 1099-1108.	0.4	5
16	Application of microcracked columnar TiO ₂ thin films deposited by DC hollow cathode plasma jet in dye-sensitized solar cells. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2017, 35, .	2.1	3
17	TiO ₂ nanoparticle detection by means of laser beam scattering in a hollow cathode plasma jet. Journal Physics D: Applied Physics, 2016, 49, 265201.	2.8	12
18	Crystalline structure and morphology of TiO ₂ thin films deposited by means of hollow cathode plasma jet with supporting anode. Surface and Coatings Technology, 2016, 291, 123-129.	4.8	14

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19	Development of a High-Frequency Emissive Probe System for Plasma Potential Measurements in a Hall Thruster. IEEE Transactions on Plasma Science, 2015, 43, 29-34.	1.3	2
20	Oxidation behavior of Cu nanoparticles embedded into semiconductive TiO ₂ matrix. Thin Solid Films, 2015, 589, 864-871.	1.8	7
21	The deposition of titanium dioxide nanoparticles by means of a hollow cathode plasma jet in dc regime. Plasma Sources Science and Technology, 2015, 24, 035025.	3.1	7
22	Magnesium plasma diagnostics by heated probe and characterization of the Mg thin films deposited by thermionic vacuum arc technology. Plasma Sources Science and Technology, 2015, 24, 035008.	3.1	12
23	Comparative measurements of plasma potential with ball-pen and Langmuir probe in low-temperature magnetized plasma. Physics of Plasmas, 2015, 22, 033516.	1.9	5
24	Investigation of ionized metal flux in enhanced high power impulse magnetron sputtering discharges. Journal of Applied Physics, 2014, 115, .	2.5	20
25	Ionized vapor deposition of antimicrobial Ti-Cu films with controlled copper release. Thin Solid Films, 2014, 550, 389-394.	1.8	29
26	Study of mass and cluster flux in a pulsed gas system with enhanced nanoparticle aggregation. Journal of Applied Physics, 2014, 116, .	2.5	12
27	Pulsed gas aggregation for improved nanocluster growth and flux. Physica Status Solidi (A) Applications and Materials Science, 2014, 211, 1189-1193.	1.8	21
28	Langmuir probe measurement of the bismuth plasma plume formed by an extreme-ultraviolet pulsed laser. Journal Physics D: Applied Physics, 2014, 47, 405205.	2.8	11
29	The time-varying electron energy distribution function in the plume of a Hall thruster. Plasma Sources Science and Technology, 2014, 23, 065001.	3.1	5
30	Experimental Study of the Discharge in the Low Pressure Plasma Jet Sputtering System. Contributions To Plasma Physics, 2013, 53, 10-15.	1.1	2
31	Application of the Ball-Pen Probe in Two Low-Temperature Magnetised Plasma Devices and in Torsatron TJ-6K. Contributions To Plasma Physics, 2013, 53, 39-44.	1.1	9
32	Time-Resolved Measurements of Plasma Properties Using Electrostatic Probes in the Cross-Field Discharge of a Hall Effect Thruster. Contributions To Plasma Physics, 2013, 53, 63-68.	1.1	2
33	Deposition of rutile (TiO ₂) with preferred orientation by assisted high power impulse magnetron sputtering. Surface and Coatings Technology, 2013, 222, 112-117.	4.8	39
34	Time-resolved Langmuir probe investigation of hybrid high power impulse magnetron sputtering discharges. Vacuum, 2013, 90, 176-181.	3.5	13
35	Measurement of the plasma and neutral gas flow velocities in a low-pressure hollow-cathode plasma jet sputtering system. Plasma Sources Science and Technology, 2013, 22, 015020.	3.1	4
36	Time-resolved measurement of plasma parameters in the far-field plume of a low-power Hall effect thruster. Plasma Sources Science and Technology, 2012, 21, 055020.	3.1	10

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37	Plasma diagnostics of low pressure high power impulse magnetron sputtering assisted by electron cyclotron wave resonance plasma. <i>Journal of Applied Physics</i> , 2012, 112, .	2.5	18
38	Electron Temperature Measurement in a Premixed Flat Flame Using the Double Probe Method. <i>Contributions To Plasma Physics</i> , 2012, 52, 692-698.	1.1	11
39	Highly ionized physical vapor deposition plasma source working at very low pressure. <i>Applied Physics Letters</i> , 2012, 100, .	3.3	27
40	Effect of mid-frequency discharge assistance on dual-high power impulse magnetron sputtering. <i>Surface and Coatings Technology</i> , 2012, 206, 2801-2809.	4.8	40
41	Growth and properties of Ti-Cu films with respect to plasma parameters in dual-magnetron sputtering discharges. <i>European Physical Journal D</i> , 2011, 64, 427-435.	1.3	29
42	Langmuir probe study of a magnetically enhanced RF plasma source at pressures below 0.1â€‰Pa. <i>Plasma Sources Science and Technology</i> , 2011, 20, 045018.	3.1	2
43	Time-Resolved Diagnostics of Dual High Power Impulse Magnetron Sputtering With Pulse Delays of 15 Åµs and 500 Åµs. <i>Contributions To Plasma Physics</i> , 2011, 51, 237-245.	1.1	26
44	Size-controlled formation of Cu nanoclusters in pulsed magnetron sputtering system. <i>Surface and Coatings Technology</i> , 2011, 205, 2755-2762.	4.8	57
45	Measurement of plasma parameters in the far-field plume of a Hall effect thruster. <i>Plasma Sources Science and Technology</i> , 2011, 20, 065012.	3.1	18
46	Spatial Distribution of Plasma Parameters in DC-Energized Hollow Cathode Plasma Jet. <i>Contributions To Plasma Physics</i> , 2010, 50, 878-885.	1.1	5
47	A Study of Plasma Parameters in Hollow Cathode Plasma Jet in Pulse Regime. <i>Contributions To Plasma Physics</i> , 2010, 50, 886-891.	1.1	4
48	Ion current to a substrate in the pulsed dc hollow cathode plasma jet deposition system. <i>Journal Physics D: Applied Physics</i> , 2010, 43, 124019.	2.8	5
49	Effect of nitrogen doping on TiO _x N _y thin film formation at reactive high-power pulsed magnetron sputtering. <i>Journal Physics D: Applied Physics</i> , 2010, 43, 285203.	2.8	46
50	Time-resolved investigation of dual high power impulse magnetron sputtering with closed magnetic field during deposition of Ti-Cu thin films. <i>Journal of Applied Physics</i> , 2010, 108, .	2.5	57
51	Does Cold Plasma Affect Breaking Dormancy and Seed Germination? A Study on Seeds of Lamb's Quarters (<i>Chenopodium album</i> agg.). <i>Plasma Science and Technology</i> , 2009, 11, 750-754.	1.5	81
52	Physical properties of homogeneous TiO ₂ films prepared by high power impulse magnetron sputtering as a function of crystallographic phase and nanostructure. <i>Journal Physics D: Applied Physics</i> , 2009, 42, 105204.	2.8	52
53	Langmuir probe diagnostics of a plasma jet system. <i>Plasma Sources Science and Technology</i> , 2009, 18, 014009.	3.1	32
54	Emissive Probe Diagnostics in Low Temperature Plasma - Effect of Space Charge and Variations of Electron Saturation Current. <i>Contributions To Plasma Physics</i> , 2008, 48, 491-496.	1.1	40

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55	Study of Electronegative Ar/O ² Discharge by Means of Langmuir Probe. Contributions To Plasma Physics, 2008, 48, 503-508.	1.1	24
56	Deposition of Ba _x Sr _{1-x} TiO ₃ thin Films by Double RF Hollow Cathode Plasma Jet System. Contributions To Plasma Physics, 2008, 48, 515-520.	1.1	3
57	Electrical Probe Diagnostics of the Hollow Cathode Plasma Jet System for Deposition of TiO _x Thin Films. Contributions To Plasma Physics, 2008, 48, 527-533.	1.1	2
58	Formation of TiO _x films produced by high-power pulsed magnetron sputtering. Journal Physics D: Applied Physics, 2008, 41, 055202.	2.8	78
59	Germination of Chenopodium Album in Response to Microwave Plasma Treatment. Plasma Science and Technology, 2008, 10, 506-511.	1.5	105
60	Measuring the Ion Flux to the Deposition Substrate in the Hollow Cathode Plasma Jet. AIP Conference Proceedings, 2008, , .	0.4	1
61	Electron kinetics in cylindrical discharges of magnetron configurations. Plasma Sources Science and Technology, 2006, 15, 228-236.	3.1	7
62	Surfatron Plasma Source Working at Frequency 2.45 GHz for Technological Applications. AIP Conference Proceedings, 2006, , .	0.4	3
63	Time-resolved probe diagnostics of pulsed DC magnetron discharge during deposition of TiO _x layers. Surface and Coatings Technology, 2006, 201, 2512-2519.	4.8	43
64	Surfatron plasma-based sterilisation. European Physical Journal D, 2006, 56, B843-B847.	0.4	6
65	Recombination of KrH ⁺ and XeH ⁺ ions with electrons in low temperature plasma. European Physical Journal D, 2006, 56, B854-B864.	0.4	5
66	Experimental investigation of the change of the electron saturation current of a dc-heated emissive probe. European Physical Journal D, 2006, 56, B932-B937.	0.4	14
67	Measurements with the emissive probe in the cylindrical magnetron. European Physical Journal D, 2006, 56, B1002-B1008.	0.4	8
68	A study of barrier-torch plasma jet system at atmospheric pressure. European Physical Journal D, 2006, 56, B1212-B1217.	0.4	6
69	Measurements of plasma parameters during Ba _x Sr _{1-x} TiO ₃ thin films deposition by double hollow cathode plasma jet system. European Physical Journal D, 2006, 56, B1283-B1289.	0.4	1
70	Investigation of the time evolution of plasma parameters in a pulsed magnetron discharge. European Physical Journal D, 2006, 56, B1364-B1370.	0.4	4
71	Observation of Wave-Like Structures in Magnetized DC Discharge in Cylindrical Symmetry in Argon. Contributions To Plasma Physics, 2006, 46, 361-366.	1.1	0
72	Probe Diagnostics of Microwave Plasma at Frequency 2.45 GHz in CW and Pulse Regime. Contributions To Plasma Physics, 2006, 46, 439-444.	1.1	4

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73	Measurement of Plasma Parameters in Low Temperature High Density Hollow Cathode Plasma Jet Working in Magnetic Field. Contributions To Plasma Physics, 2006, 46, 445-450.	1.1	5
74	Modeling and Diagnostic of the Plasma of Magnetic Field Supported Discharges. Contributions To Plasma Physics, 2005, 45, 319-327.	1.1	3
75	Characterization of a Magnetron Plasma for Deposition of Titanium Oxide and Titanium Nitride Films. Contributions To Plasma Physics, 2005, 45, 348-357.	1.1	31
76	Comparative measurements of the plasma potential with the ball-pen and emissive probes on the CASTOR tokamak. European Physical Journal D, 2005, 55, 235-242.	0.4	41
77	Measurement of the Parameters of Atmospheric-Pressure Barrier-Torch Discharge. Plasma Processes and Polymers, 2005, 2, 501-506.	3.0	22
78	A novel approach to direct measurement of the plasma potential. European Physical Journal D, 2004, 54, C95-C99.	0.4	50
79	A study of discharge fluctuations in magnetically-supported dc discharge in cylindrical and inverted cylindrical configuration. European Physical Journal D, 2004, 54, C735-C741.	0.4	1
80	Investigation of plasma parameters in the DC planar magnetron in balanced and unbalanced mode. European Physical Journal D, 2004, 54, C822-C827.	0.4	4
81	Diagnostics of surfatron-generated plasma by probe measurements and emission spectroscopy. European Physical Journal D, 2004, 54, C970-C975.	0.4	3
82	Monte Carlo Simulations of the Electron Currents Collected by Electrostatic Probes. Contributions To Plasma Physics, 2004, 44, 577-581.	1.1	11
83	2-D Experimental Study of the Plasma Parameter Variations of the Magnetically Sustained DC Discharge in Cylindrical Symmetry in Argon. Contributions To Plasma Physics, 2004, 44, 613-618.	1.1	8
84	Langmuir probe diagnostic for measurement of recombination rates of positive ions with electrons in stationary afterglow system. Vacuum, 2004, 76, 457-463.	3.5	2
85	Fluctuations of the magnetically-supported dc discharge in coaxial configuration. Vacuum, 2004, 76, 437-445.	3.5	3
86	Probe diagnostics of the RF barrier-torch discharge at atmospheric pressure. Surface and Coatings Technology, 2003, 174-175, 530-534.	4.8	14
87	Two-dimensional nonlocal model of axially and radially inhomogeneous plasma of cylindrical magnetron discharge. Physical Review E, 2003, 68, 016401.	2.1	8
88	Emissive probe measurements of plasma potential fluctuations in the edge plasma regions of tokamaks. Review of Scientific Instruments, 2003, 74, 1583-1587.	1.3	35
89	PIC-MCC Modeling of the Cylindrical Magnetron Discharge. AIP Conference Proceedings, 2003, , .	0.4	0
90	Experimental Study of Axial Plasma Parameter Variations in the Cylindrical Magnetron Discharge. AIP Conference Proceedings, 2003, , .	0.4	0

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91	Measurements of the Fluctuation-Induced Flux with Emissive Probes in the CASTOR Tokamak. AIP Conference Proceedings, 2003, , .	0.4	0
92	Applicability of Electron Emissive Probes for Plasma Potential and Electric Field Measurements in Magnetized Plasmas. AIP Conference Proceedings, 2003, , .	0.4	0
93	Kinetic Modeling Of Axially Non-Uniform Cylindrical Magnetron Discharge. AIP Conference Proceedings, 2003, , .	0.4	0
94	Recombination of D ³⁺ ions in the Afterglow of a He-Ar-D ₂ Plasma. Physical Review Letters, 2002, 88, 044802.	7.8	29
95	Measurements with an emissive probe in the CASTOR tokamak. Plasma Physics and Controlled Fusion, 2002, 44, 567-578.	2.1	90
96	The Radio Frequency Hollow Cathode Discharge Induced by the RF Discharge in the Plasma-Jet Chemical Reactor. Contributions To Plasma Physics, 2002, 42, 119-131.	1.1	3
97	Advanced integrated stationary afterglow method for experimental study of recombination of processes of H ³⁺ and D ³⁺ ions with electrons. International Journal of Mass Spectrometry, 2002, 218, 105-130.	1.5	80
98	Fluctuation measurements with emissive probes in tokamaks. European Physical Journal D, 2002, 52, 1115-1120.	0.4	6
99	Kinetic simulation model of magnetron discharges. Physical Review E, 2001, 63, 056408.	2.1	24
100	Experimental study of recombination of H ³⁺ ions with electrons relevant for interstellar and planetary plasmas. Journal of Physics B: Atomic, Molecular and Optical Physics, 2001, 34, L485-L494.	1.5	29
101	The recombination of H ³⁺ ions with electrons: dependence on partial pressure of H ₂ . Chemical Physics Letters, 2000, 331, 209-214.	2.6	44
102	Advanced Integrated Stationary Afterglow apparatus for study of recombination in He ⁺ Ar ⁺ H ₂ plasma. European Physical Journal D, 2000, 50, 329-334.	0.4	7
103	A novel system for studies of dc discharge in cylindrical magnetron. European Physical Journal D, 2000, 50, 419-426.	0.4	4
104	A study of the DC discharge in a cylindrical magnetron comparison of experiment and a pic model. European Physical Journal D, 2000, 50, 427-432.	0.4	5
105	Title is missing!. European Physical Journal D, 1999, 49, 483-498.	0.4	11
106	Title is missing!. European Physical Journal D, 1999, 49, 1685-1701.	0.4	1
107	Radial behaviour of the electron energy distribution function in the cylindrical magnetron discharge in argon. Journal Physics D: Applied Physics, 1999, 32, 2655-2665.	2.8	24
108	The high pressure torch discharge plasma source. Plasma Sources Science and Technology, 1999, 8, 15-21.	3.1	22

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109	Apparatus and experimental method for measurements of the potential distributions in dc glow discharges. Review of Scientific Instruments, 1998, 69, 2037-2044.	1.3	4
110	An experimental study of plasma density determination by a cylindrical Langmuir probe at different pressures and magnetic fields in a cylindrical magnetron discharge in heavy rare gases. Journal Physics D: Applied Physics, 1997, 30, 1763-1777.	2.8	80
111	Langmuir Probe Diagnostics for Medium Pressure and Magnetised Low-Temperature Plasma. European Physical Journal Special Topics, 1997, 07, C4-397-C4-411.	0.2	15
112	The Interaction of the Supersonic Plasma Jet with the Substrate in the RF Plasma Chemical Reactor. Contributions To Plasma Physics, 1996, 36, 605-611.	1.1	9
113	The Influence of Collisions in the Space Charge Sheath on the Ion current Collected by a Langmuir Probe. Contributions To Plasma Physics, 1995, 35, 3-14.	1.1	17
114	Langmuir Probe Determination of Charged Particle Number Density in a Flowing Afterglow Plasma. Contributions To Plasma Physics, 1995, 35, 503-516.	1.1	19
115	Radio-frequency low pressure supersonic jet plasma chemical system. Surface and Coatings Technology, 1995, 74-75, 212-214.	4.8	7
116	A Method for the Ion Density Estimation from the Double Probe Data at Medium and Higher Pressures. Contributions To Plasma Physics, 1994, 34, 51-57.	1.1	6
117	A Collisional Model of the Positive Ion Collection by a Cylindrical Langmuir Probe. Contributions To Plasma Physics, 1994, 34, 59-68.	1.1	48
118	Simple Physical Model of Generation of the Low Pressure Radio Frequency Supersonic Plasma Jet. Contributions To Plasma Physics, 1994, 34, 749-764.	1.1	10
119	A Study of the Gas Flow in the RF Low Pressure Supersonic Jet Plasma Chemical System. Contributions To Plasma Physics, 1994, 34, 765-772.	1.1	21
120	SIFT studies of the reactions of rare gas atomic ions with Cl ₂ and Br ₂ . International Journal of Mass Spectrometry and Ion Processes, 1993, 129, 155-162.	1.8	7
121	The reactions of positive and negative halogen ions with Cl ₂ and Br ₂ . Journal of Chemical Physics, 1993, 98, 8660-8666.	3.0	17
122	Langmuir Probe Determination of Charged Particles Density in an rf Discharge. Contributions To Plasma Physics, 1991, 31, 43-47.	1.1	3
123	Comment on determination of electron temperature from Langmuir probe data in tokamak edge plasma. European Physical Journal D, 1990, 40, 678-685.	0.4	1
124	The use of Langmuir Probe Methods for Plasma Diagnostic in Middle Pressure Discharges. Contributions To Plasma Physics, 1990, 30, 167-184.	1.1	17
125	The Application of Langmuir Probes to the Measurements in Flowing Afterglow Plasma. Contributions To Plasma Physics, 1990, 30, 185-192.	1.1	6
126	A Probe Method for Determination of time Evolution of Metastable Atoms Density in a Flowing Afterglow Plasma. Contributions To Plasma Physics, 1990, 30, 437-448.	1.1	7

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127	Radiative lifetimes of vibrationally excited HCl+ ($\tilde{v} = 1$) and DCl+ ($\tilde{v} = 1$) ions. International Journal of Mass Spectrometry and Ion Processes, 1990, 97, 203-210.	1.8	7
128	Selected ion flow drift tube studies of the reaction of HBr+ with various neutral molecules. International Journal of Mass Spectrometry and Ion Processes, 1990, 97, 211-218.	1.8	8
129	An absolute proton affinity scale in the ~ 140 kcal mol ⁻¹ range. Journal of Chemical Physics, 1989, 91, 4037-4042.	3.0	75
130	The application of a selected-ion flow drift tube to the determination of proton affinity differences. International Journal of Mass Spectrometry and Ion Processes, 1989, 93, 165-175.	1.8	8
131	Vibrational quenching of HCl+ ($\tilde{v} = 1$) and DCl+ ($\tilde{v} = 1$) by Ar and Kr. Chemical Physics Letters, 1988, 144, 131-135.	2.6	15
132	Influence of metastable-metastable collisions on electron distribution function in afterglow. European Physical Journal D, 1988, 38, 47-52.	0.4	2
133	SIFDT studies of the reactions of N ⁺ ions with H ₂ , D ₂ , and Ar. International Journal of Mass Spectrometry and Ion Processes, 1987, 81, 235-246.	1.8	24
134	The thermal energy reactions HCl+ + SF ₆ $\hat{\rightarrow}$ SF ₅ + + HF + Cl and HCl+ + CF ₄ $\hat{\rightarrow}$ CF ₃ + + HF + Cl. International Journal of Mass Spectrometry and Ion Processes, 1987, 79, 231-235.	1.8	41
135	Method for measuring the electron distribution function in the low temperature plasma with a high time resolution. European Physical Journal D, 1987, 37, 179-187.	0.4	0
136	A contribution to the study of the influence of metastables in the flowing afterglow plasma. European Physical Journal D, 1987, 37, 188-193.	0.4	11
137	Measurements of the reaction rate coefficients of the endoergic reactions C+(² P) + H ₂ (D ₂) $\hat{\rightarrow}$ CH+(CD+) + H(D) from threshold to centre-of-mass energy 0.8 eV. International Journal of Mass Spectrometry and Ion Processes, 1986, 74, 251-263.	1.8	31
138	A contribution to the assessment of the influence of collisions on the measurements with Langmuir probes in the thick sheath working regime. European Physical Journal D, 1985, 35, 988-1006.	0.4	48
139	Measurement of the electron distribution function in flowing afterglow plasma by means of Langmuir probe. European Physical Journal D, 1983, 33, 1226-1229.	0.4	6
140	The energy dependence of some neon-ion-neutral reaction rate coefficients investigated in a flow-drift tube experiment. Journal of Physics B: Atomic and Molecular Physics, 1981, 14, 2719-2729.	1.6	16
141	Production of metastable O ⁺ * in the reaction between He ⁺ and O ₂ at 300K. Journal of Physics B: Atomic and Molecular Physics, 1979, 12, 2947-2950.	1.6	6
142	The rate coefficients for several ternary association reactions of CH ₃ ⁺ in the temperature range 100 $\hat{\rightarrow}$ 300 K. Chemical Physics Letters, 1979, 63, 166-170.	2.6	26
143	A study of the reactions of the ground and metastable states of C ⁺ , N ⁺ , S ⁺ and N ₂ ⁺ at 300 K. International Journal of Mass Spectrometry and Ion Physics, 1979, 29, 231-247.	1.3	103
144	Contribution to the electron energy distribution function measurement in the afterglow discharge. European Physical Journal D, 1978, 28, 1335-1341.	0.4	6

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145	Apparatus for the electron energy distribution function measurement in the afterglow discharge. European Physical Journal D, 1977, 27, 1027-1033.	0.4	1
146	Time resolved measurements in the Ne positive column IV. Study of the electron distribution function in low-pressure arc. European Physical Journal D, 1972, 22, 264-269.	0.4	1
147	The dependence of the electron distribution function on the discharge current in Ne and Ne-He discharge. European Physical Journal D, 1972, 22, 52-57.	0.4	5
148	Time resolved measurements of the electron energy distribution in unstable plasma I. Measurement technique. European Physical Journal D, 1971, 21, 62-70.	0.4	10
149	Time resolved measurements of the energy distribution in unstable plasma II. Measurement in the ionization waves. European Physical Journal D, 1971, 21, 71-76.	0.4	3
150	Electronic method for direct display of the electron energy distributions in plasma. European Physical Journal D, 1971, 21, 794-798.	0.4	12